Title	層状 族モノカルコゲナイド薄膜のファンデルワール スヘテロ界面微細構造に関する研究
Author(s)	米澤,隆宏
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Description	 Supervisor:高村 由起子,先端科学技術研究科,博士



氏 名 澤 隆 宏 位 学 類 博士(マテリアルサイエンス) 0 学 位 뭉 博材第 490 号 記 学位授与年月 日 令和2年3月25日 層状Ⅲ族モノカルコゲナイド薄膜のファンデルワールスへテロ界面 論 文 題 目 微細構造に関する研究 文 查 委 員 主査 高 村 由起子 北陸先端科学技術大学院大学 准教授 大 島 文 同 教授 義 正彦 司 富 取 教授 博 司 水 田 教授 上 野 啓 司 埼玉大学 教授

論文の内容の要旨

Owing to a wide range of physical properties tunable through their composition, the number and stacking of layers, and the intralayer structures, layered materials (LMs) are of great interest for various applications in electronic, optical and thermoelectric devices. The absence of dangling bonds at the surface of individual layers allows LMs for being epitaxially grown on various templates via weak van der Waals (VDW) interaction regardless of the lattice mismatch, which is called "VDW epitaxy (VDWE)". Since the 1980's, a lot of examples of growth of LMs on different materials by VDWE have been reported. However, the growth of large-scale single-crystalline films remains a key challenge. Also, the atomic structure near the film-substrate interface is poorly documented, in spite of its strong influence on the crystallographic structure of the LMs thin films. In this study, gallium and indium selenide (GaSe and InSe) thin films were grown on semiconducting substrates such as Ge(111) and GaAs(111) by molecular-beam epitaxy (MBE). GaSe and InSe are semiconducting LMs with great expectations for optical and electronic devices. The thin film structures were analyzed using X-ray diffraction (XRD), reflection high-energy electron diffraction (RHEED), scanning tunneling microscopy (STM), atomic force microscopy (AFM) and scanning transmission electron microscopy (STEM).

Chapters 1 and 2 of the thesis give, respectively, a general introduction of this research and a description of the experimental methods.

Chapter 3 presents the investigation of the VDWE growth of GaSe and InSe thin films. The thin films were grown with the substrate temperature Tsub. between 300 °C and 550 °C and with different ratios of the evaporation rates of Se and Ga or In. The growth of single crystalline thin films was found to require a fine tuning of the growth conditions. Ga- and In-rich conditions gave rise respectively to Ga droplets and to elongated crystallites in the InSe thin films. In contrast, Se-rich phases like Ga2Se3 or α -, β -, γ -In2Se3 and In3Se4 form under Se-rich or low Tsub. conditions. The growth of single-phase GaSe thin films was found to require Se-rich conditions and Tsub. set between 400 °C and 550 °C. Almost perfect

single-phase InSe thin films with the best crystallographic quality were obtained for balanced evaporation rates of In and Se and a relatively high Tsub. of 500 °C. GaSe and InSe thin films were grown with (Ga, In)Se(0001) // Ge(111) and (Ga, In)Se[1120] // Ge[110] epitaxial relationships. In addition, a strong temperature dependence of the terrace shape of the GaSe thin films was found: The shape of the terrace edges changes from rounded hexagonal to triangular when Tsub is increased from 400 °C to 500 °C.

In chapter 4, suitability of sample thinning process based on focused-ion beam milling for plan-view STEM observations of Moiré patterns resulting from the overlapping of a LM thin film and a substrate is demonstrated. Then, an accurate determination of the local variation of the in-plane orientation of GaSe thin films with respect to the Ge(111) substrate by means of STM and plan-view STEM is presented. The Moiré pattern observed by plan-view STEM confirms an almost perfect GaSe[112\overline{0}] // Ge[11\overline{0}] epitaxial relationship. Meanwhile, Moiré patterns observed by STM indicate the existence, locally at the interface, of small in-plane deviations from this orientation. These results indicate that the local misorientations of LMs at the nucleation stage disappear with the increased number of layers.

In chapter 5, the investigation of the atomic structures near the interface between the GaSe or InSe thin films and the Ge(111) or GaAs(111) substrates observed by cross-sectional STEM is presented. Strain-free GaSe and InSe thin films were grown with the same optimized condition on Ge(111) and on the As face of GaAs(111). The epitaxial relationship of (Ga, In)Se(0001) // GaAs(111) and (Ga, In)Se[1120] // GaAs[110] was adopted. The dangling bonds of the Ge(111) were terminated by a half GaSe or InSe monolayer and those of the GaAs(111) were terminated by Se atoms. The GaSe and InSe individual layers adopted the expected trigonal prismatic structure, but also a non-prismatic (NP) structure, which has not been reported yet. Since the NP layers were formed regardless of the type of substrate and the lattice mismatch, it is likely that they are stabilized by the growth conditions: Single-phase NP GaSe thin films were grown with Se-rich conditions and low Tsub. The rounded hexagonal shape of GaSe islands shown in chapter 3 can be explained by the formation of the NP GaSe phase in the thin film.

These achievements contribute to a better knowledge and understandings of the structures of GaSe and InSe thin films, their growth conditions and formation mechanism in VDWE. The discovery of novel NP GaSe and InSe phases suggests that the world of LMs is much richer than expected.

Keywords: GaSe, InSe, VDW epitaxy, STEM, Moire pattern, Layered materials, MBE, SPM

論文審査の結果の要旨

層状物質は、主にファンデルワールス力などの弱い力を介して積層するため、格子不整合の制 約を殆ど受けずに幅広い異種基板上にヘテロ積層、及び、ヘテロ成長することが可能である。そ の物性は低次元性を反映した特異性を有し、組成、積層、層数、層内構造、異種材料間の組み合 わせに応じて多様に変化する。これらの特長から層状物質やその単位層である原子層薄膜の新 奇物性の解明と電子デバイス応用に関する研究が、近年、世界で大きく注目されている.

本論文は,半導体層状物質として,優れた光応答性/非線形光学特性,および,電子伝導特性を 有し, 次世代光・電子デバイスへの応用が期待される GaSe と InSe に着目している. これらの薄 膜の将来的な実用化や既存の半導体技術との融合を見据え、半導体単結晶基板上へのエピタキ シャル成長技術の確立に向けたファンデルワールスヘテロ界面微細構造の形成過程や成長条件 依存性を系統的に、詳細に調べている. 具体的には、分子線エピタキシー法により Ge(111)基板 や GaAs(111)基板上に成長させた GaSe 薄膜および InSe 薄膜のヘテロ界面を原子分解能走査透過 電子顕微鏡(STEM)や超高真空走査プローブ顕微鏡を駆使して実空間観察し,評価・解析を行な っている. その結果、GaSe 及び InSe 薄膜成長時の析出相や表面界面局所微細構造、それらの成長 条件依存性に関して,原子レベルでの知見を得ている.また,従来困難であった,ファンデルワ ールスエピタキシーにおいて核生成段階の成長環境がヘテロ界面微細構造に及ぼす影響の評価 と考察、に加えて、局所面内配向性の実空間観察と定量評価、その成長ダイナミクスに関する評 価と考察を成し遂げている. 特に後者は、主に本研究により確立された、STEM によるモアレパ ターンを利用した局所面内配向性の実空間観察評価手法によって得られた成果である. この手 法は層状物質薄膜の品質を大きく左右する局所面内配向性や境界欠陥に関する情報を高分解能 で定量的に取得可能であり、かつ、他の様々な層状物質薄膜に適用可能な優れた手法である. さ らに特筆すべきことに、STEMによる原子分解能断面構造観察を通じて、いまだかつて報告され たことのない非柱状構造を有する GaSe と InSe の結晶多形を発見している. 特に,非柱状 GaSe 相に関してはその単相成長条件の特定に成功しており、この相の伝導・光学特性の評価やデバイ ス応用研究への展開を可能とした.

以上,本論文は, GaSe 薄膜および InSe 薄膜のファンデルワールスエピタキシーにおける薄膜-基板界面を原子レベルで実空間観察することに成功し,その成長過程に関して重要な新たな知見を多数得ている.また,新たな結晶多形の発見とその単相成長に成功しており、学術的に貢献するところが大きい.よって,博士(マテリアルサイエンス)の学位論文として十分価値あるものと認めた.